

Device and Method for Reducing a Wedge Error

Abstract

This invention relates to a device for opposite alignment of a first surface (2o) of a first substrate (2) with a second surface (5o) of a second substrate (5) with a gap between the first and the second surfaces (2o, 5o) with the following features:

- A first retaining system (1) for retaining the first substrate (2) on a first retaining surface (1a),
- A second retaining system (6) for retaining the second substrate (5) on a second retaining surface (6a),
- Approach means for causing the first surface (2a) to approach the second surface (5a) in one direction of translation (T) as far as into one end position, characterized in that there are means for reducing a wedge error between the first and second surfaces (2o, 5o) during the approach of the first surface (2o) to the second surface (5o).

This invention furthermore relates to a method for opposite alignment of a first surface of a first substrate with a second surface of a second substrate with a gap between the first and the second surfaces, characterized in that a wedge error between the first and the second surfaces is reduced during the approach of the first surface to the second surface.

Figure 1.